

Thin Film - XRD

Applications Training Class

P/N 862-872400

Bruker AXS Inc

Madison, WI Training Center

Class Size

Because our trainings are interactive and learner-oriented, we limit class size to a minimum of three and a maximum of six. Early enrollment is encouraged as registrations are accepted on a first-come/first-serve basis. We reserve the right to cancel a course if there are less than three registrants four weeks prior to the start date.

Attendance Fee*

The course fee is \$1,700 USD per attendee per two-day session.

Bruker Training Facility

Bruker AXS Inc
5465 East Cheryl Pkwy
Madison, WI 53711-5373
USA
1 (800) 234- XRAY

*Each participant will be provided with class materials, computer and lunch.

Course Options

High Resolution Diffraction (Monday/Tuesday), 9am-4pm

This training course will show the theoretical fundamentals and data collection strategies for high resolution X-ray diffraction with the D8 family of diffractometers. The main focus is on the analysis of epitaxial thin films using the DIFFRAC.SUITE software packages including DIFFRAC.LEPTOS H.

X-ray Reflectometry (XRR) and Grazing Incidence Diffraction (GID) (Wednesday/Thursday), 9am-4pm

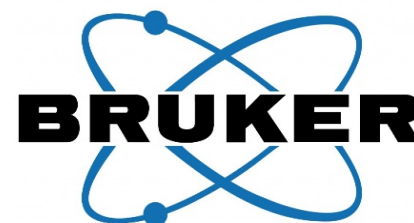
This training course will show the different methods used for X-ray reflectometry (XRR) and grazing incidence diffraction (GID) measurement and analysis, including the DIFFRAC.EVA and DIFFRAC.XRR software packages. The course is intended for users with experience in XRD, new users are strongly encouraged to first attend the X-ray Power Diffraction or High Resolution Diffraction course.

For Course Questions Please Contact:

Ben Krueger, Applications Scientist, XRD
Benjamin.Krueger@bruker.com

For Registration and Other Questions:

Caitlin Heitman, Marketing Specialist
Training.baxs.us@bruker.com



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